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CENTRAL INTELLIGENCE AGENCY
INFORMATION REPORT

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COUNTRY	East Germany	REPORT	
SUBJECT	VEB Carl Zeiss, Jena: 1956 Production Planning for the Precision Mechanics Division	DATE DISTR.	23 September 1955
		NO. OF PAGES	2
DATE OF INFO		REQUIREMENT NO.	RD
PLACE ACQUIRED		REFERENCES	
DATE ACQUIRED			

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This is UNEVALUATED Information

THE SOURCE EVALUATIONS IN THIS REPORT ARE DEFINITIVE.
THE APPRAISAL OF CONTENT IS TENTATIVE.
(FOR KEY SEE REVERSE)

1. The following is a list of all major devices and items which comprise the 1956 production plan of the Precision Mechanics (Fe - Feinmechanik) Division of VEB Carl Zeiss, Jena, as of 1 August 1955. No major changes in the plan were contemplated as of that date.

ITEM	No. of Units
Optimeter (with an accuracy of 1 Mu)	100
Projector Optimeter (0.2 Mu)	100
Abbe-Laengenmesser, vertical (up to 100 millimeters)	75
Universal lengthmeter (Universal Laengenmesser)	250
Interference Comparator (Inko), e.g., for Cadmium light	20
Measuring Device (Messmaschine), 1-meter	30
Messmaschine, 3-meter	20
Messmaschine, 6-meter	2
Measuring Microscope (Type 0/50)	100
Universal tool microscope (Werkzeugmikroskop), small	200
Universal shop microscope, large	300
Universal measuring microscope (Universal Messmikroskop)	175
Abbe-Comparator (Two scales, front scale adjustable)	50

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(Note: Washington distribution indicated by "X"; Field distribution by "#".)

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ITEM	No. of Units
Einbau-Mikroskop, with adjustable eyepiece (Microscope to be mounted in a grinding machine manufactured by the Lindner firm)	100
Einbau-Mikroskop, with stable eyepiece	100
BL-2 (for drilled jig of the Hille, Dresden firm)	20
Einstellmikroskop (Type Mk-2)	20
Einstellmikroskop (Type Mk-4)	8
Optical Angle-Measuring Device	1000
Angle Level (Winkel-Libelle)	150
Optical Dividing Devices (large)	150
Optical Dividing Devices (small)	75
Camshaft Testing Device	40
Coincidence Level (Koinzidenz-Libelle)	175
Surface testing device (Oberflaechenpruefgeraet), after Prof. Schmaltz	200
Impact and centering testing device (Schlagfehler-pruefgeraet)	100
Evolent testing device (Evolventenpruefgeraet)	25
Alignment testing telescope (Fluchtfernrohr)	75
Thread-measuring wires with hooks (Gewindemes-sadrahte)	5400 (sets)
Thread measuring wires with eyes (Gewindemes-sadrahte)	6300 (sets)

2. 1956 production programs for minor items such as micrometer measuring clocks have not yet been definitely decided upon.

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